

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: Gelatos et al.	Group Art Unit 3742
Serial No: 10/792,054 Confirmation No: 4738	Examiner: Sang Yeop Paik
Filed: March 2, 2004	Attorney Docket No: 008682 USA/CPI/WCVD/PJS
For: Heated Ceramic Substrate Support with Protective Coating	August 31, 2007 San Francisco, California

**RESPONSE TO NOTIFICATION OF NON-COMPLIANT APPEAL BRIEF**

VIA ELECTRONIC FILING

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

ATTENTION: Board of Patent Appeals and Interferences

**APPELLANT'S AMENDED BRIEF (37 C.F.R. § 41.37)**

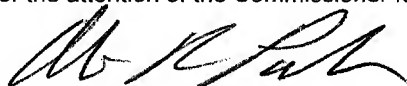
This brief is in response to the Notification of Non-Compliant Appeal Brief, mailed on August 1, 2007, and is being timely filed within one month of the Notification.

In accordance with MPEP 1205.03, Appellant is providing solely a summary of the claimed subject matter as required by 37 CFR § 41.37(c)(1)(v).

**CERTIFICATE OF TRANSMISSION**

I hereby certify that this correspondence is being electronically filed via PAIR with the United States Patent and Trademark Office, for the attention of the Commissioner for Patents, on the date shown below.

By:



Alison R. Parker

Date: August 31, 2007

**V. SUMMARY OF CLAIMED SUBJECT MATTER (37 C.F.R. § 41.37(c)(1)(v))**

Independent claim 1 is to a substrate support **20** for a substrate processing chamber (Page 1, lines 7-8). The substrate support comprises a ceramic block **28** having a substrate receiving pocket **24** that is sized to receive a substrate **21** therein (Page 5, lines 5-10), a peripheral ledge **23** extending about the substrate receiving pocket **24**, and side surfaces **29** (Page 5, lines 12-17 and lines 22-25); a ceramic coating **40** covering the substrate pocket **24** and peripheral ledge **23** of the ceramic block **28** (Page 6, lines 1-9, and FIG.2B), the ceramic coating **40** comprising an amorphous Si-H-N-O compound (Page 8, lines 12-24); a resistance heater **32** in the ceramic block **28** (Page 10, lines 29-30, and Page 11, lines 14-15); and heater leads extending out of the ceramic block **28** to conduct electrical power to the resistance heater **32** (Page 10, lines 32-34).

Independent claim 11 is to a substrate support **20** for a substrate processing chamber (Page 1, paragraph 1, lines 7-8). The substrate support comprises a ceramic block **28** having a substrate receiving pocket **24** that is sized to receive a substrate **21** therein (Page 5, lines 5-10), a peripheral ledge **23** extending about the substrate receiving pocket **24**, and side surfaces **29** (Page 5, lines 12-17 and lines 22-25); a silicon nitride compound coating covering the substrate pocket **24** and peripheral ledge **23** of the block **28** (Page 6, lines 1-9, page 7, line 29 - page 8, line 2); a resistance heater **32** in the block **28** (Page 10, lines 29-30, and Page 11, lines 14-15); heater leads extending out of the block **28** to conduct electrical power to the resistance heater **32** (Page 10, lines 32-34).

Independent claim 18 is to a substrate support **20** for a substrate processing chamber (Page 1, lines 7-8). The substrate support **20** comprises a block **28** comprising a first ceramic, the block **28** having a substrate receiving pocket **24** that is sized to receive a substrate **21** therein (Page 5, lines 5-10), a peripheral ledge **23**

extending about the substrate receiving pocket **24**, and side surfaces **29** (Page 5, lines 12-17 and lines 22-25); a coating comprising a second ceramic that is a different ceramic than the first ceramic, the coating covering the substrate pocket **24** and peripheral ledge **23** of the block **28** (Page 6, lines 1-9, and FIG.2B), and the second ceramic comprising an amorphous Si-H-N-O compound or silicon nitride compound (Page 8, lines 12-24); a resistance heater **32** in the block **28** (Page 10, lines 29-30, and Page 11, lines 14-15); a gas energizer electrode **36** in the block **28** (Page 12, lines 17-29); and heater and electrode leads extending out of the block **28** to conduct power to the resistance heater **32** and gas energizer electrode **36**, respectively (Page 10, lines 21-23 and lines 32-34, and Page 12, lines 19-23).

## CONCLUSION

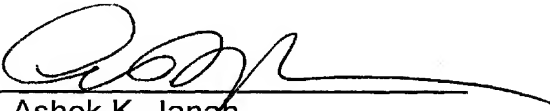
Appellant respectfully requests entry of the foregoing amended summary of claimed subject matter.

Should the Examiner have any questions, the Examiner is requested to telephone Appellant's representative at the number listed below.

Respectfully submitted,

JANAH & ASSOCIATES  
A PROFESSIONAL CORPORATION

Date: 8/31/2007

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